National Aeronautics and Space Administration



## Taking SiC Power Devices to the Final Frontier: Addressing Challenges of the Space Radiation Environment

Jean-Marie Lauenstein and Megan Casey NASA Goddard Space Flight Center (GSFC)

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#### **Abbreviations & Acronyms**



Acronym	Definition	
BJT	Bipolar Junction Transistor	
$BV_{DSS}$	Drain-Source Breakdown Voltage	
COR	Contracting Officer Representative	
COTS	Commercial Off The Shelf	
ESA	European Space Agency	
ETW	Electronics Technology Workshop	
FY	Fiscal Year	
GCR	Galactic Cosmic Ray	
I <sub>D</sub>	Drain Current	
I <sub>DSS</sub>	Drain-Source Leakage Current	
I <sub>G</sub>	Gate Current	
I <sub>R</sub>	Reverse-Bias Leakage Current	
IC	Integrated Circuit	
ICSCRM	International Conference on SiC and Related Materials	
JAXA	Japan Aerospace Exploration Agency	
JBS	Junction Barrier Schottky	
JFET	Junction Field Effect Transistor	
LBNL	Lawrence Berkeley National Laboratory cyclotron facility	

Acronym	Definition	
MOSFET	Metal Oxide Semiconductor Field Effect Transistor	
Q	Charge	
RADECS	Radiation and its Effects on Components and Systems	
RHA	Radiation Hardness Assurance	
SBD	Schottky Barrier Diode	
SEB	Single-Event Burnout	
Si	Silicon	
SiC	Silicon Carbide	
SMU	Source Measurement Unit	
SOA	State Of the Art	
STMD	Space Technology Mission Directorate	
SWAP	Size, Weight, And Power	
TAMU	Texas A&M University cyclotron facility	
TID	Total Ionizing Dose	
VDMOS	Vertical Double-diffused MOSFET	
V <sub>DS</sub>	Drain-Source Voltage	
$V_{GS}$	Gate-Source Voltage	
V <sub>R</sub>	Blocking Voltage	
V <sub>TH</sub>	Gate Threshold Voltage	

#### **Motivational Factors**



Images courtesy of NASA



Orion





High Voltage Instruments



Solar Electric Propulsion



Commercial Space

- Game-changing NASA approaches are demanding higher-performance power electronics
  - SEE rad-hardened high-current MOSFETs > 250 V do not exist
  - High-voltage transistors with fast switching speeds are also needed
- SWAP benefits for existing technologies
  - SiC power devices are flying now (Orion, MMS)

**Conclusions:** We must understand the risk of damaged parts

We must support industry/government/academic partnerships to expand SEE hardening efforts

#### **Radiation Effects in SiC Power Technology**



- Wide-bandgap power electronics are frequently referred to as "inherently radiation hard" – but to what type of radiation?
  - Total ionizing dose (TID)
  - Displacement damage dose (DDD)
  - Heavy-ion induced single-event effects (SEE)
- Prior work by NASA and other researchers has shown that serendipitously SEE-hard commercial SiC power devices are rare or non-existent

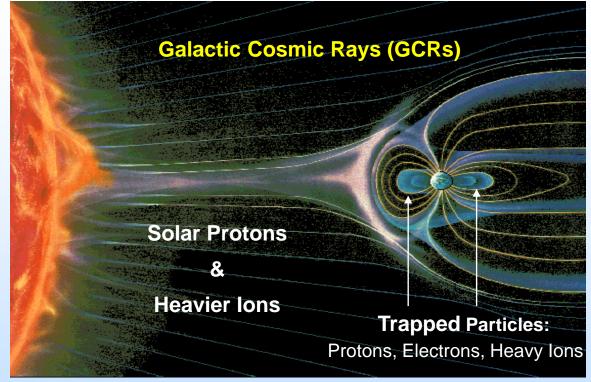
TID hardness came for "free"; SEE hardness will not!

Device Type	# COTS or Engineering Parts/ # Manufacturers
Diode	6/4
MOSFET	8/4
JFET	4/2
BJT	1/1

SiC parts included in this talk:

## **Space Radiation Environment**

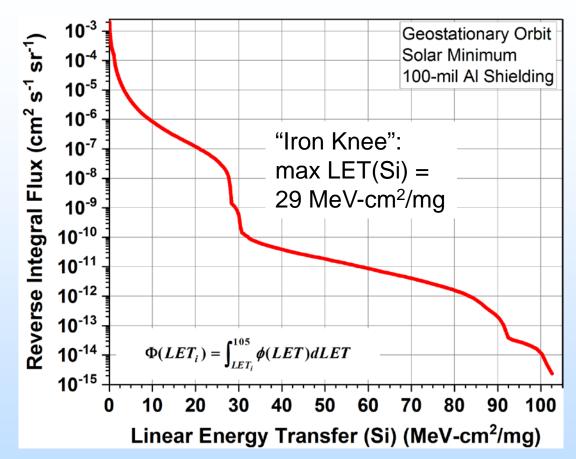




After K. Endo, Nikkei Science Inc. of Japan

- Cumulative effects
  - TID—Total Ionizing Dose (degradation due to charge trapped in device oxides)
  - DDD—Displacement Damage Dose (degradation from damage to semiconductor)
- Single-particle effects
  - SEE—Single-Event Effect (change in performance of device resulting from passage of a single energetic particle)

## **Heavy-Ion Environment**

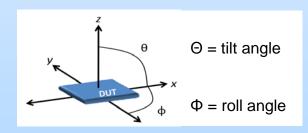


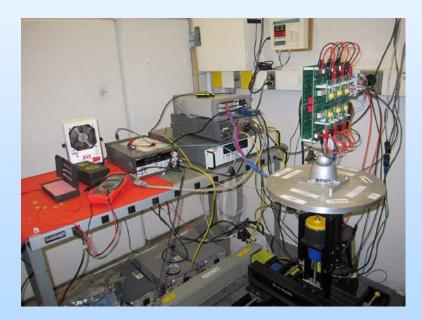
SEE radiation requirements are derived in part by the environment specified as a function of linear energy transfer (LET) in silicon; SiC test results therefore are in LET(Si)

#### SiC Power Device Response to Heavy Ion Irradiation



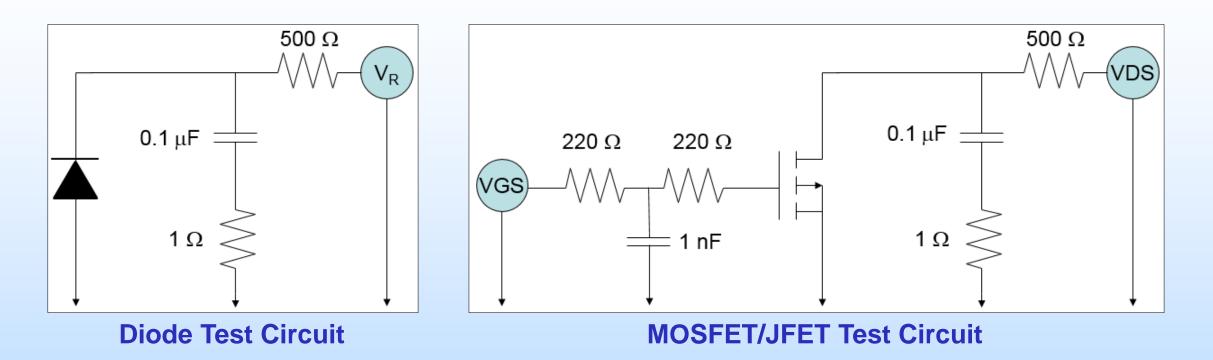
- Heavy-ion radiation effects in SiC power devices are a function of:
  - Applied voltage
    - Reverse voltage ( $V_R$ ) or drain-source voltage ( $V_{DS}$ ) when in the "off" or blocking state
  - Incident ion energy and species
    - Linear energy transfer (LET)
  - Angle of ion strike
    - Tilt/roll angle
  - Device temperature





#### **Test Circuits**





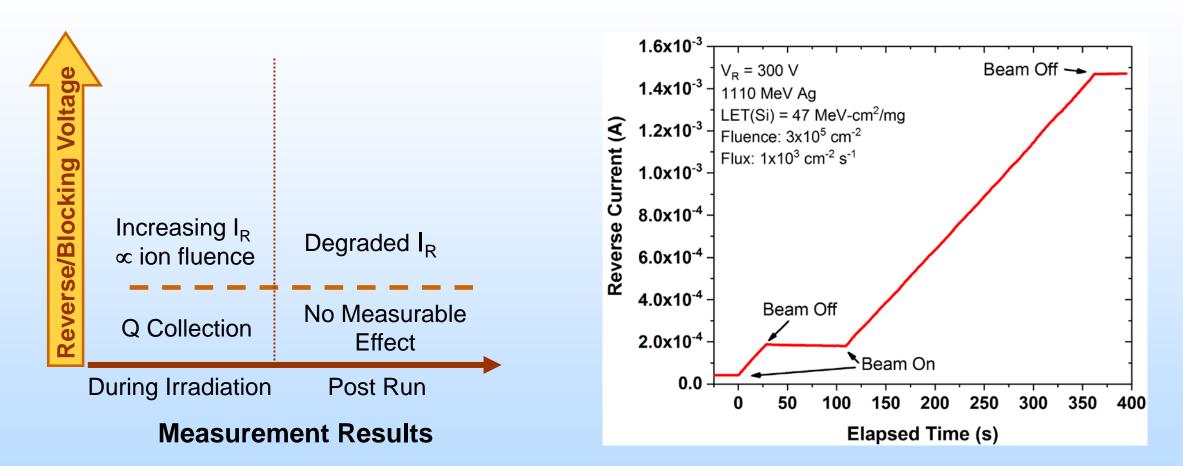
- Per MIL-STD 750, TM1080
  - Stiffening capacitor prevents voltage sagging upon sudden increase in current
  - Gate filter to protect MOSFET oxide from electrically induced transients
    - Filter removed for BJT tests



## Applied Voltage and Ion LET: SCHOTTKY DIODES

#### **Diode Effects as a Function of V<sub>R</sub>: Degradation**



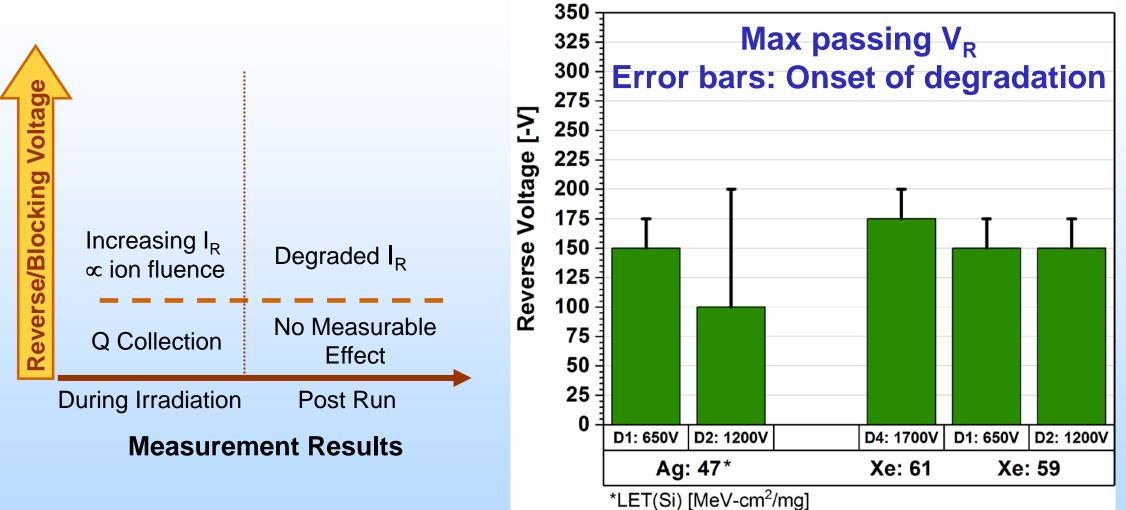


#### Leakage current increases linearly with ion fluence; Slope increases with increasing V<sub>R</sub>

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#### **Diode Effects as a Function of V<sub>R</sub>: Degradation**

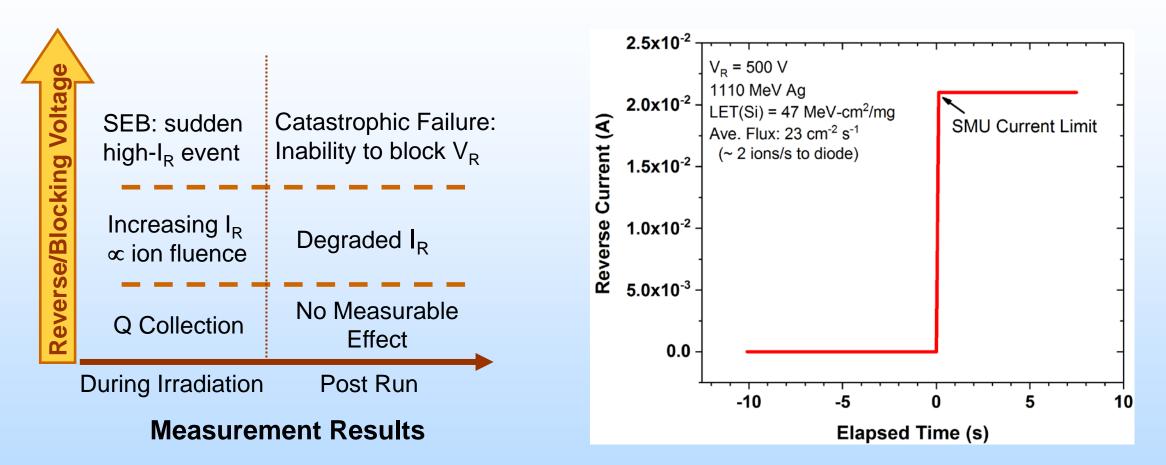




Onset V<sub>R</sub> for degradation is similar for 650 V – 1700 V SBD or JBS diodes: Once minimum conditions met, electric field may not matter

### **Diode Effects as a Function of V<sub>R</sub>: SEB**

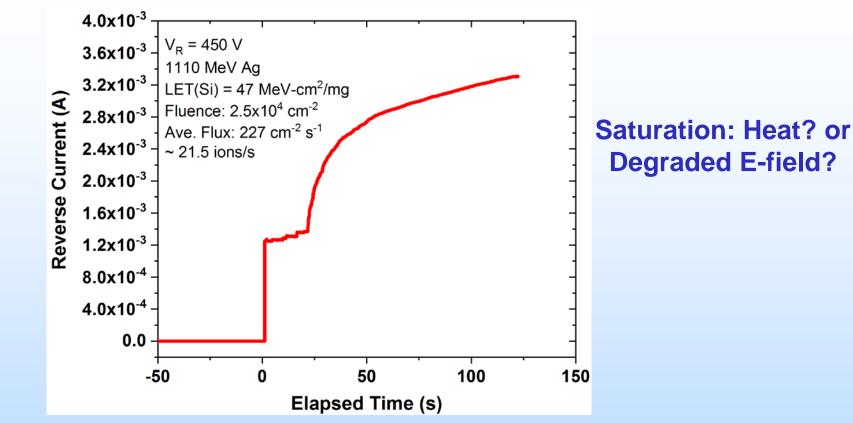




#### After catastrophic single-event burnout (SEB), the diode can no longer block voltage

#### **Diode Effects as a Function of V<sub>R</sub>: Test Challenge**



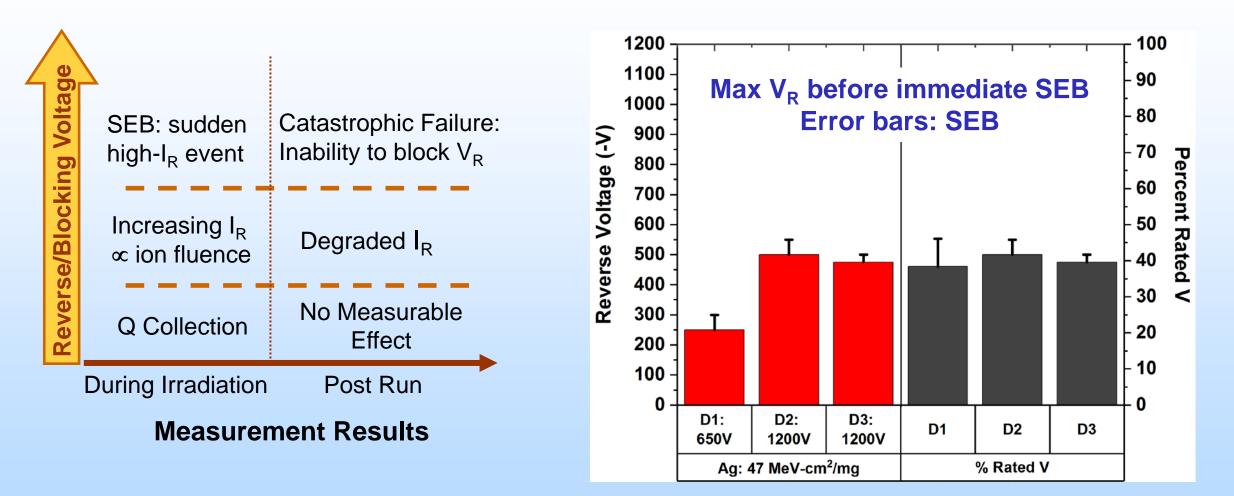


Degradation is non-Poisson process: Prior damage can impact effect of next ions. Threshold for SEB can be affected, preventing accurate identification of "SEB-safe" region of operation\*.

\*see Kuboyama, IEEE Trans. Nucl. Sci. 2006.

#### **Diode Effects as a Function of V<sub>R</sub>: SEB**

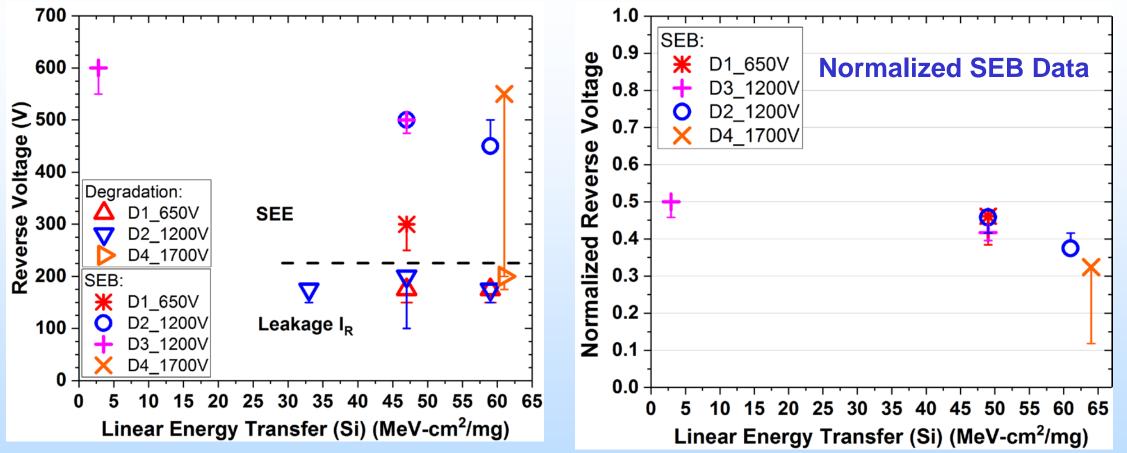




650 V – 1700 V Schottkys show SEB at similar % of rated  $V_R$ : Electric field dependent

#### **Schottky Diode Effects as a Function of LET**



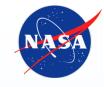


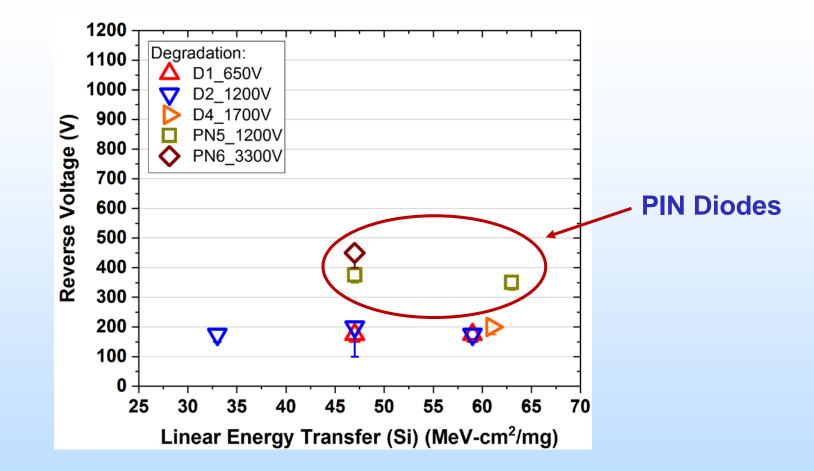
No degradation with neon at LET = 2.8 MeV-cm<sup>2</sup>/mg but SEB still occurs at 50% of rated  $V_R$  despite very low LET Suggests high-energy protons will cause SEB



## Applied Voltage and Ion LET: PIN DIODES

#### **PIN vs. Schottky Diode Effects: Degradation**

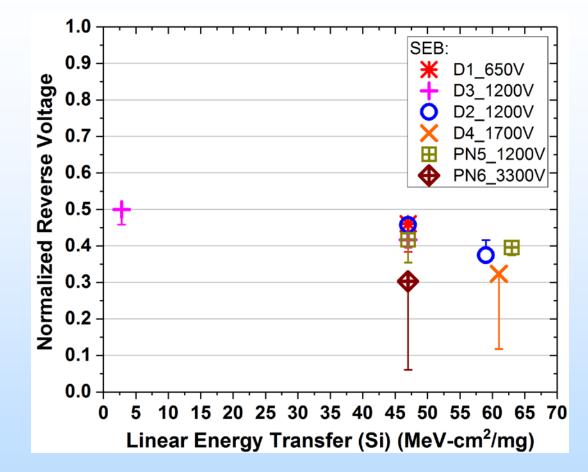




PIN diode onset  $V_R$  for degradation is higher than that for Schottkys. Similar degradation onset  $V_R$  for 1200 V and 3300 V PINs

#### **PIN vs. Schottky Diode Effects: SEB**





PIN and Schottky diode SEB occurs at similar normalized  $V_R$  – Again suggests different mechanisms for SEB vs. degradation

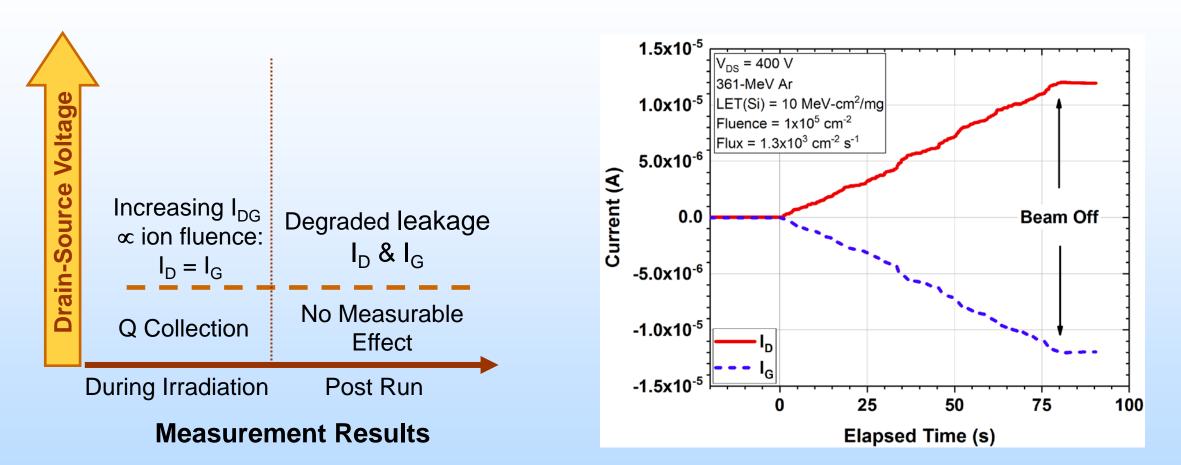


#### **Applied Voltage:**

**JFETS** 

#### Effects as a Function of $V_{DS}$ at Fixed off $V_{GS}$ : Degradation

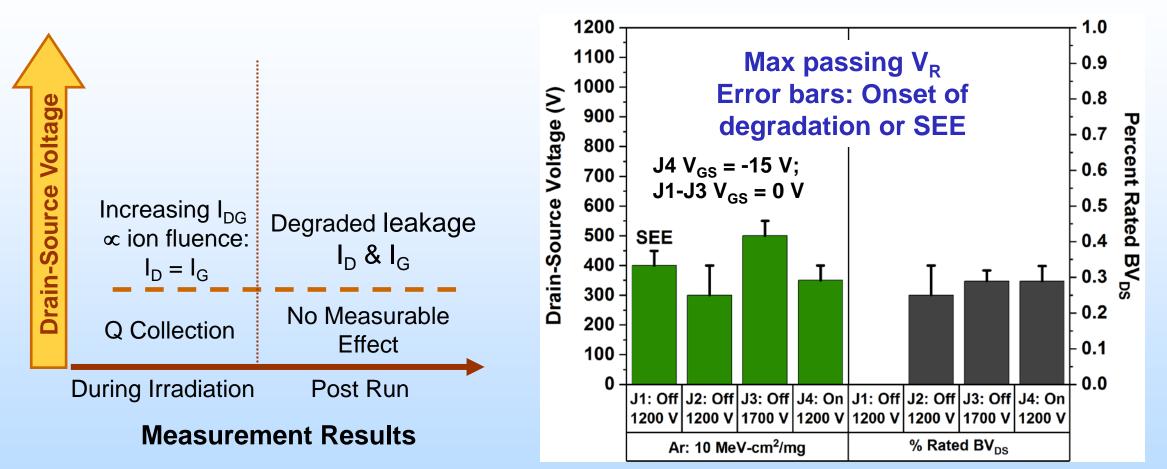




Degradation in tested normally-on and normally-off JFETs is always drain-gate leakage, likely due to trench design

# **Effects as a Function of V\_{DS} at Fixed off V\_{GS}: Degradation**

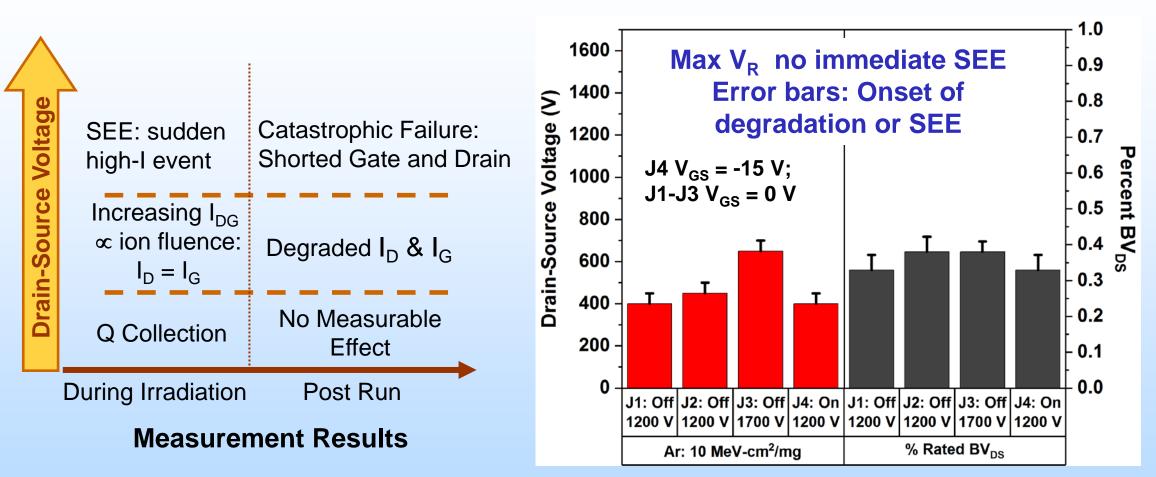




Onset V<sub>DS</sub> for degradation is similar for normally-on and normally-off JFETs Possibly greater field dependence of degradation mechanism vs. diodes (or due to lower test LET?)

#### Effects as a Function of $V_{DS}$ at Fixed off $V_{GS}$ : SEE





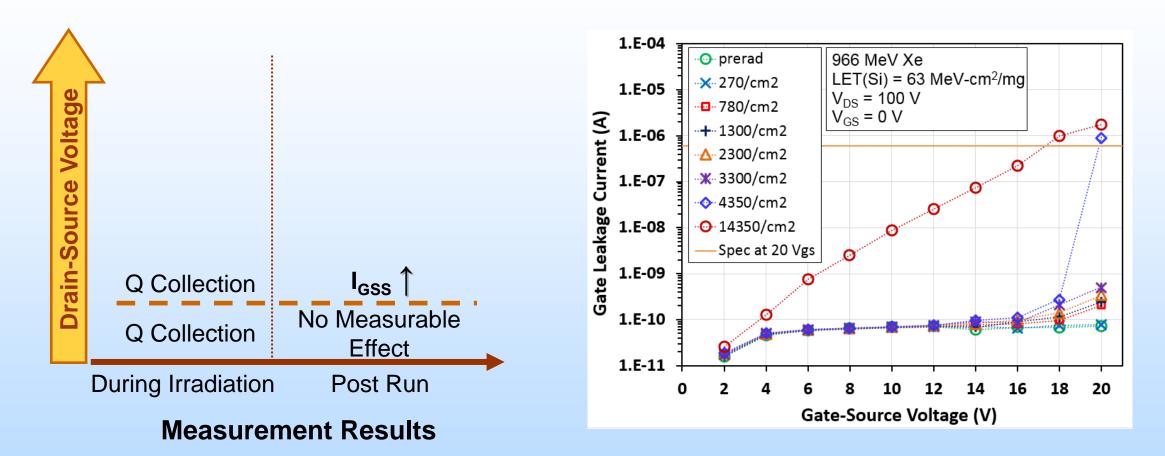
1200 V – 1700 V JFETs show SEE at similar % of rated V<sub>DS</sub> Normally-on similar to normally-off JFET susceptibility



## Applied Voltage and LET: MOSFETS

#### Effects as a Function of $V_{DS}$ at $V_{GS} = 0$ V: Latent Gate Damage

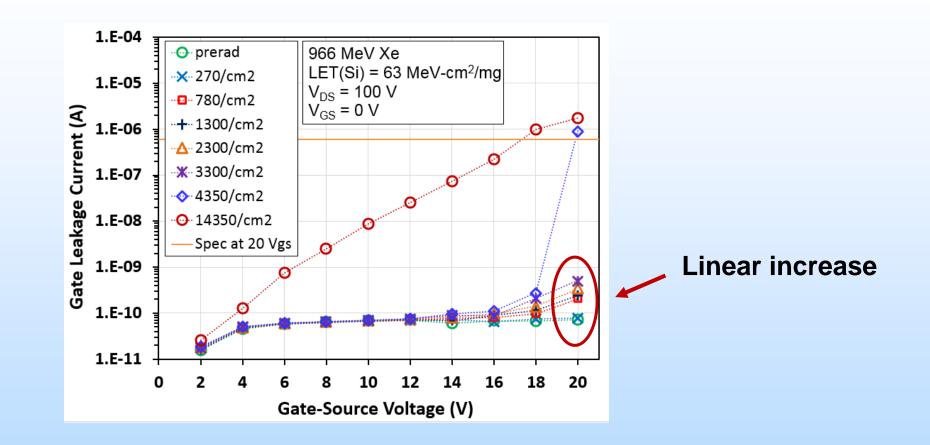




Presence of gate oxide introduces a latent-damage mechanism revealed only on post-irradiation gate stress (PIGS) test

#### Effects as a Function of $V_{DS}$ at $V_{GS} = 0$ V: Latent Gate Damage

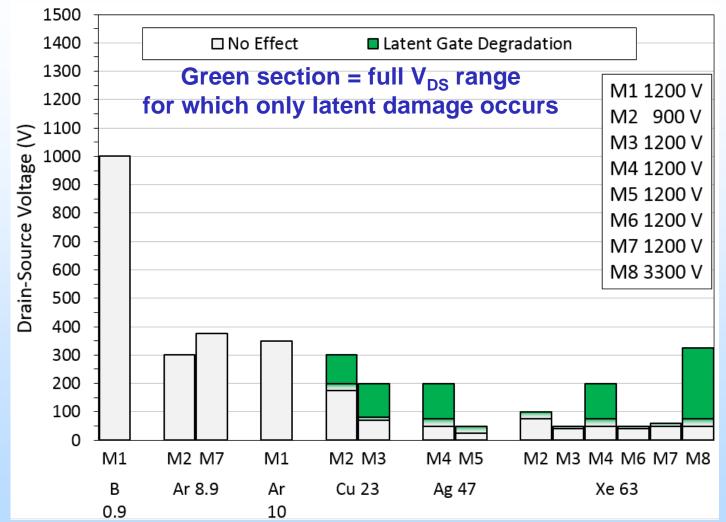




Gate Leakage Current (I<sub>GSS</sub>) initially increases linearly with fluence but then thermal damage likely occurs

#### Effects as a Function of V<sub>DS</sub> at V<sub>GS</sub> = 0 V: Latent Gate Damage

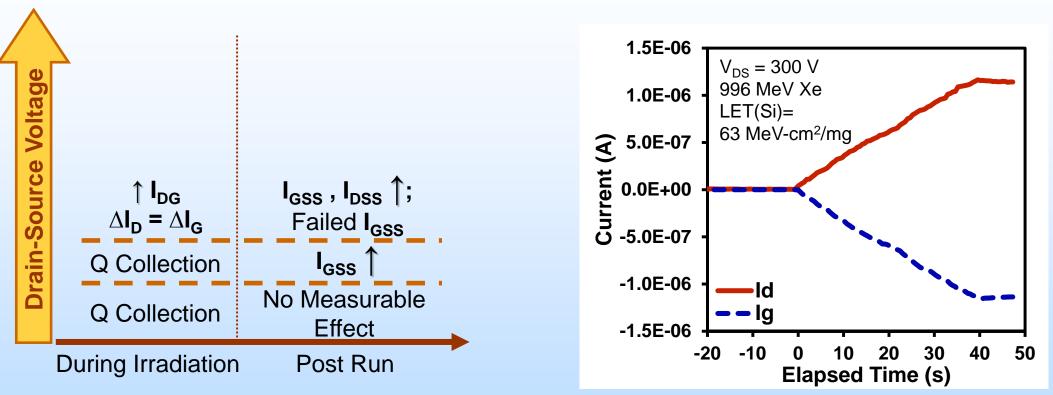




#### Latent gate damage is LET/ion species-dependent; Onset is independent of voltage rating at higher LETs

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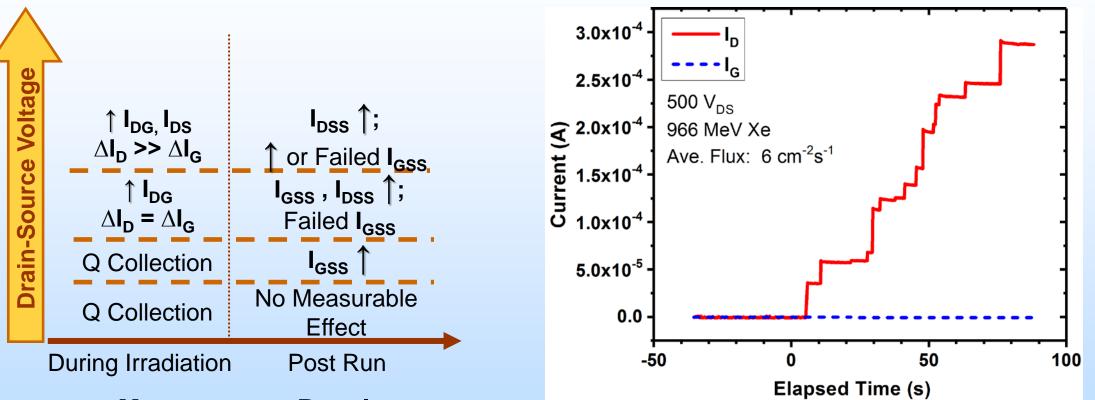
#### Effects as a Function of $V_{DS}$ at $V_{GS} = 0$ V: Degradation During Beam Run



#### **Measurement Results**

Gate oxide degradation is linear with ion fluence Slope is a function of V<sub>DS</sub> and ion LET/species

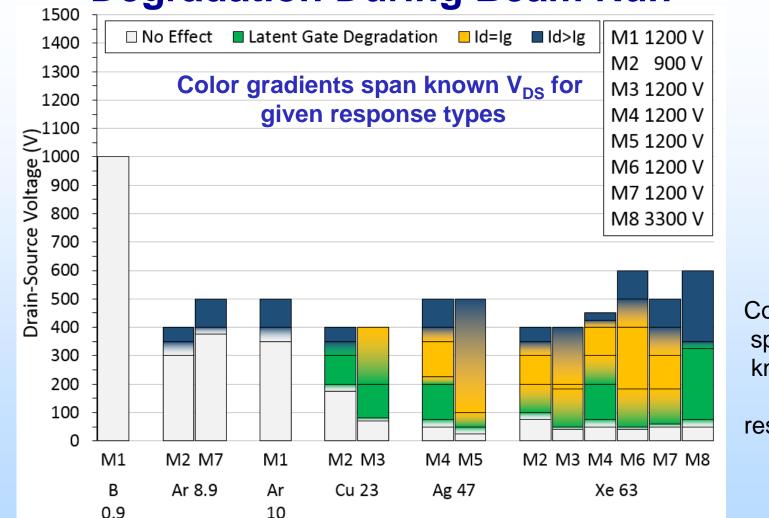
#### Effects as a Function of $V_{DS}$ at $V_{GS} = 0$ V: Degradation During Beam Run



#### **Measurement Results**

Unlike vertical JFET topology, planar-gate MOSFETs show drain-source leakage current. Very low flux reveals damage from individual ion strikes.

#### Effects as a Function of $V_{DS}$ at $V_{GS} = 0$ V: Degradation During Beam Run

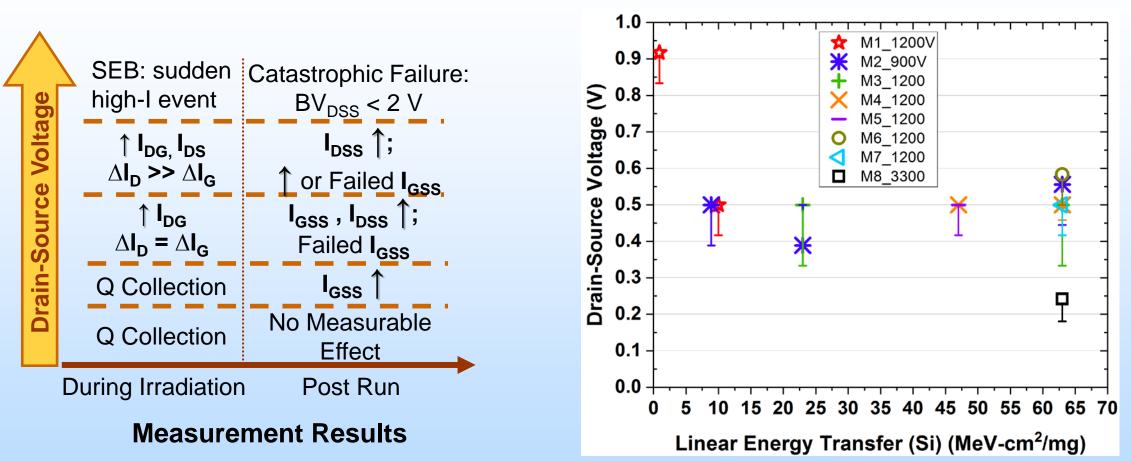


Color gradients span between known V<sub>DS</sub> for given response types

Not all MOSFETs suffer drain-gate leakage current degradation: Per ICSCRM MO.DP.14 (Zhu, et al.), likely a "JFET" drain neck width factor

#### Effects as a Function of $V_{DS}$ at $V_{GS} = 0$ V: SEB

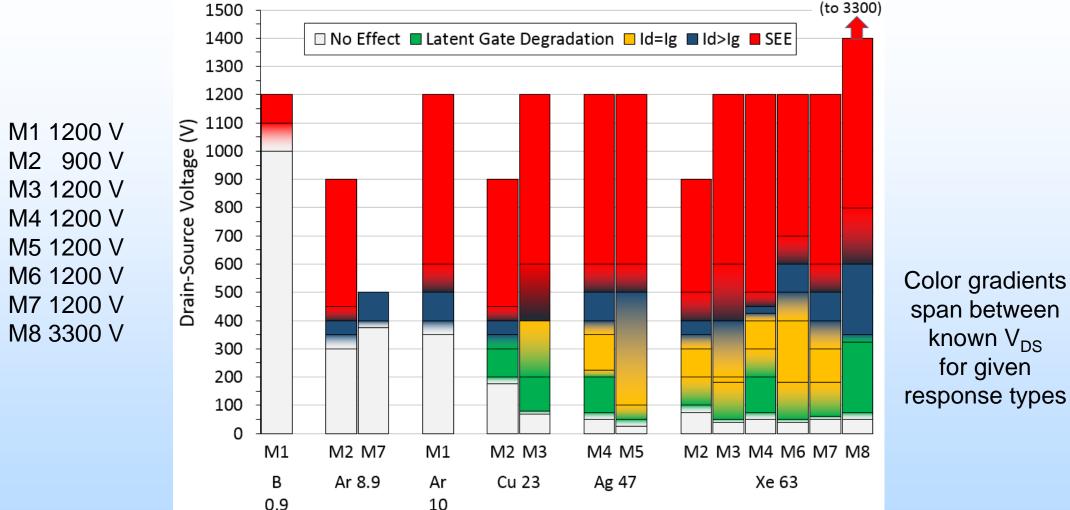




Use of real BV<sub>DS</sub> will likely strengthen similarity across MOSFETs of different ratings. SEB vulnerability saturates before the GCR flux "iron knee".

#### **Effects as a Function of V\_{DS} at V\_{GS} = 0 V**

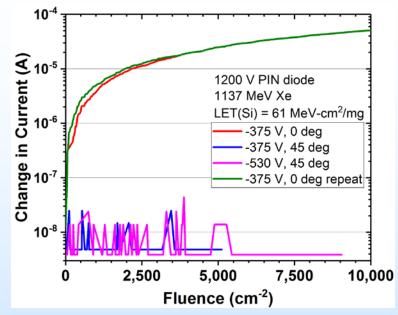




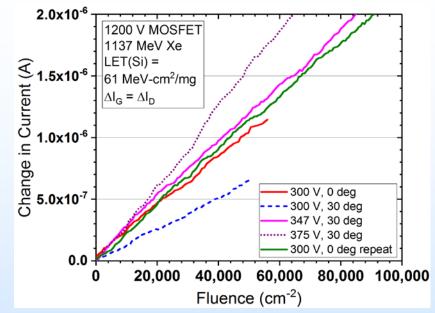
Drain-source leakage current degradation is least influenced by electric field and ion LET; it may be more closely linked to material properties

## **Angle of Ion Incidence**





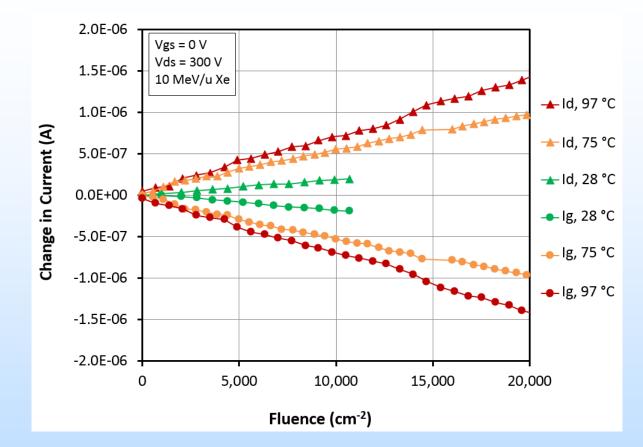
- Diode: Strong angle effect
  - At given  $V_R$ , no degradation at 45°
  - Matching vertical component of electric field has no impact
    - Cosine law not followed



- MOSFET: Follows cosine law when gate-leakage dominated
  - For I<sub>G</sub> = I<sub>D</sub> degradation signature, path length through gate likely dominates angle effect
  - For drain-source current degradation dominant region/device, expect behavior similar to diode response

#### **Temperature Effects: Power MOSFET**





## Rate of leakage current degradation in a 1200-V power MOSFET increases with increasing temperature.

## **Summary & Conclusions**



- All discrete, unhardened SiC power devices in this work exhibit catastrophic failure at 50% of rated voltage or below
  - Electric field and ion LET/species are shown to impact this threshold.
  - LET/species effects are quickly saturated below the high-flux iron knee of the GCR spectrum
    - Mission orbit will have a weaker influence on risk
- Non-catastrophic damage occurs at voltages as low as 10% of rated values (gate oxide latent damage effects), and 30% for nonoxide degradation effects.
  - Degradation within the SiC material is not correlated significantly with electric field strength and thus may require other methods than doping or geometry changes.
  - Reliability studies will be important to understand the impact of degradation mechanisms on long-term mission reliability
- Due to saturation effects at high LETs, performance discrimination may best be achieved by testing at LETs below those dictated by typical space mission radiation requirements.

## **Summary & Conclusions**



Angle effects – Diodes and MOSFETs:

- Both Schottky and PIN diodes exhibit faster roll-off of degradation effects with angle of incidence than would be expected if the vertical component of the electric field were the critical component of the mechanism.
  - This lack of strong field dependence is also seen at normal angle of incidence when comparing effects in diodes of different voltage ratings.
- Additional angle studies are needed in transistor devices.
  - Gate oxide leakage effects follow the cosine relationship of the vertical field as expected from historic silicon studies.

#### **Temperature - MOSFETs:**

- For case temperatures up to 100 °C, rate of I<sub>DG</sub> degradation increases.
  - More studies are needed for non-oxide leakage pathways.